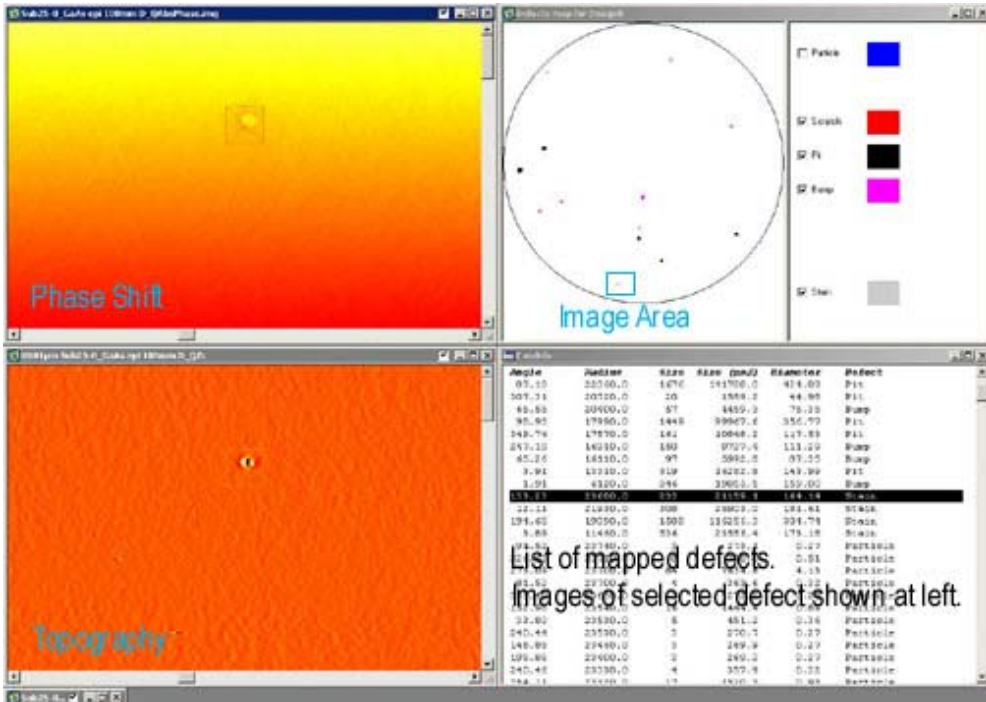


Gallium Arsenide Epi Defects

KLa-Tencor's Candela Optical Surface Analyzers (OSA) system can be used for both polished GaAs wafers and epi wafers. Defects on the substrate, whether topographic or non-topographic, can develop into defects in the epilayer. These epi defects are often discontinuities in the epilayers, easily recognized in the phase shift and topography images. In contrast, the scattered light image alone cannot differentiate between an epi defect and particle.



Below: Epi defect caused by film residue present on the GaAs substrate.

